

PATENT APPLICATION

AUG 22 2005

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

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| In re United States Patent Application of: | Docket No.: | ATMI-668 (7493) |
| Applicants: | Conf. No.: | 4823 |
| Application No.: | Art Unit: | 1752 |
| Date Filed: | Examiner: | LE, Hoa Van |
| Title: | Customer No.: | 25559 |
| COMPOSITION AND PROCESS FOR POST-ETCH REMOVAL OF PHOTORESIST AND/OR SACRIFICIAL ANTI- REFLECTIVE MATERIAL DEPOSITED ON A SUBSTRATE | | |

FACSIMILE TRANSMISSION CERTIFICATE

ATTN: Examiner Hoa Van Le
Fax No. (571) 273-8300

I hereby certify that this document is being filed in the United States Patent and Trademark Office, via facsimile transmission to Mail Stop Amendment, Commissioner for Patents, PO Box 1450, Alexandria, VA 22313-1450, on August 22, 2005 to United States Patent and Trademark Office facsimile transmission number (571) 273-8300.

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Number of Pages

Tristan A. Fuierer

August 22, 2005

Date _____

**AMENDMENT RESPONDING TO JUNE 2, 2005 OFFICE ACTION
IN UNITED STATES PATENT APPLICATION NO. 10/792,038**

**Mail Stop Amendment
Commissioner for Patents
PO Box 1450
Alexandria, VA 22313-1450**

Sir:

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This responds to the June 2, 2005 Office Action in the above-identified application.

PATENT APPLICATION

Please amend the claims of the application as set out in the following **Section I (Amendments to the Claims)**.

Remarks addressing the substance of the June 2, 2005 Office Action are set out in the **Section II (Remarks)** hereof.